



**Harvesting the potential of self-assembly**

Marcel Tichem, Delft University of Technology  
 IMAPS-Benelux Spring event, June 9, 2011 – Holst Centre

TU Delft  
 Challenge the Future

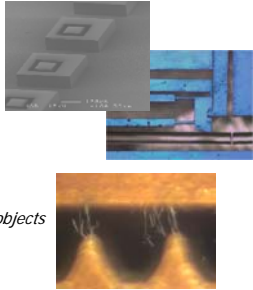
**Precision and Microsystems Engineering:  
 the ultimate in mechanical engineering**

Micro- and Nano Devices and Systems	Micro- and Nano engineering Urs Staufer	Mechatronic System Design Rob Munnig Schmidt, Jan van Eijk(PT)	Precision equipment
	Applied Mechanics Daniel Rixen, Fred van Keulen		

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**Research program micro- and nano-  
 scale assembly**

- Extreme precision  
*Photonic alignment and fixing  
 with sub- $\mu\text{m}$  precision*
- Extreme quantities  
*Self-assembly at micro-scale*
- Extreme small length scale  
*Discrete patterns of nano-scale objects*



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**Contents**

- The self-assembly concept
- Illustration: electrostatic self-alignment
- Chip2Foil: ultra thin chip assembly to polymer foils
- Self-assembly towards industrialisation

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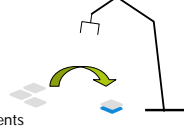
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**Self-assembly**

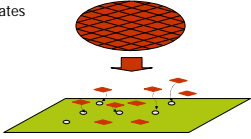
- Self-assembly is the autonomous assembly of parts into structures
- Contrast with "classic" assembly  
 Parts move due to force field rather than direct, contact-based position control
- Expected benefits:
  - High throughput against low cost by massive parallelisation
  - (High) precision against low cost
  - Ability to handle very small scale components



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### General self-assembly scheme

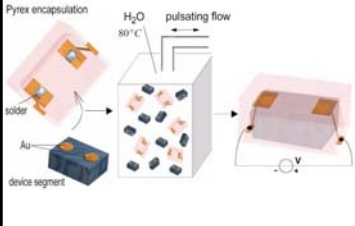
- At least one of the parts is put in random motion (usually – there is a form of self-assembly which uses hinging structures)
- Parts to be mated are provided with entrapment or binding sites, exploiting a force field which effectuates
  - Trapping
  - Alignment
  - Locking / bonding
- Various physical mechanisms may be exploited in the realisation of suitable binding sites



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### Self-assembly

Shape-and-solder directed self-assembly



- Cr/Au deposition
- spin resist and pattern
- etching and Cr/Au removing
- TiCu deposition and etching
- Spin PR and pattern clip into solder bath

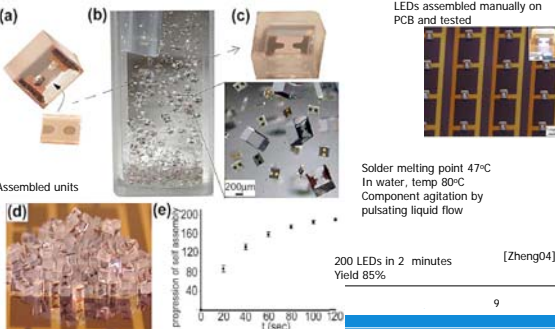
Processing of encapsulation units

[Zheng04]

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### Self-assembly

Shape-and-solder directed self-assembly



Assembled units

LEDs assembled manually on PCB and tested

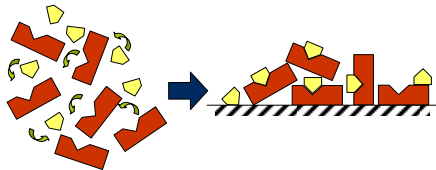
Solder melting point 47°C  
 In water, temp 80°C  
 Component agitation by pulsating liquid flow

200 LEDs in 2 minutes  
 Yield 85%

[Zheng04]

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### Logistic concept of this approach



- Efficient *sub*-operation
- Must fit in total process flow to harvest potential

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### Alternative main logistic approach and an implementation

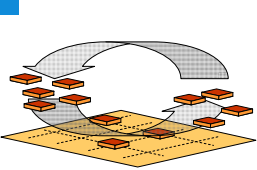
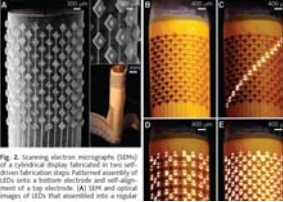



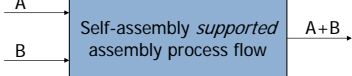
Fig. 2. Scanning electron micrographs (SEMs) of a cylindrical display fabricated on two self-driven fabrication steps. Left: self-assembly of LEDs onto a bottom electrode and self-alignment of a top electrode. Right: SEM and optical images of LEDs that assembled into a regular array.

- “Flushing” parts over a surface with trapping sites

[Jacobs2002]

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### Self-assembly concept



Assembly = handling and joining  
*feeding, gripping, manipulating and placing, joining, adding substances, adjusting, ...*

⇒ self-assembly is about the part handling; sometimes bonding and/or electrical interconnection steps are integrated

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### Self-assembly concept

Various physical principles can be used to create the required force field

- self-assembly requires "field generator"
- self-assembly often requires adaptations to the parts to make them susceptible to the exploited field

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### Self-assembly concept

To exploit the benefits of self-assembly, the right logistic concept must be chosen

- self-assembly requires careful integration into total process flow: What is the expected contribution from self-assembly? How can the benefits be harvested?

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### Assembly task

- Chip to chip assembly
  - Pick and place of individual chips → throughput and cost per operation limitation
  - Wafer to wafer transfer followed by dicing ("hamburger approach") → limited to matching wafer and chip size, issue of "bad chips"

[Kurniawan2010]

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### Approach: pre-alignment on intermediate carrier

Pre-alignment of chips on temporary intermediate carrier

Batch transfer of pre-aligned chips to target substrate (wafer)

Self-assembly

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### Carrier

Carrier

Corona wire  $V_{hw} = -6kV$

Grid  $V_g = 159-600V$

Electric charge

Carrier

SiO<sub>2</sub> pattern charged with corona charging

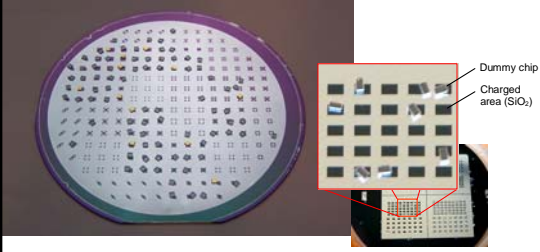
Carrier vibration for chip mobility

3D view

Top view

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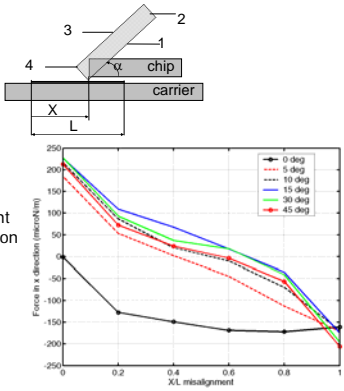
### First alignment results



Dummy chip  
 Charged area (SiO<sub>2</sub>)

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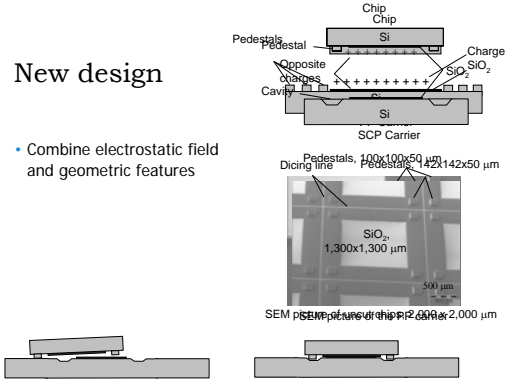
### Modelling



Vertical force >> aligning force  
 No unique and constant alignment force direction

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### New design

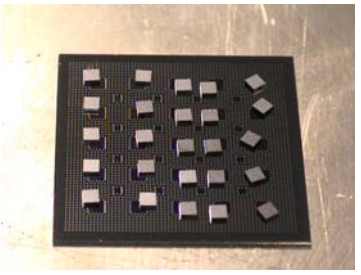


Chip  
 Chip Si  
 Pedestal  
 Opposite Charges  
 Cavity  
 Charge SiO<sub>2</sub>  
 Si  
 SCP Carrier  
 Pedestals, 100x100x50 μm  
 Dicing line  
 Pedestals, 42x142x50 μm  
 SiO<sub>2</sub>, 1,300x1,300 μm  
 500 μm  
 SEM picture of the chip 2,000x2,000 μm

- Combine electrostatic field and geometric features

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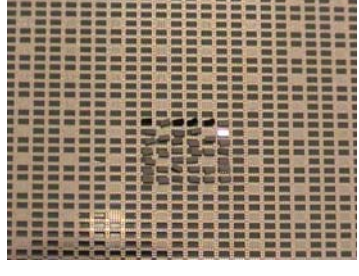
### Results (April 2009)



25 chips, ~2x2mm, coarsely pre-positioned (manually)  
 To final state in ~15 seconds

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### Results (November 2009)



~40 chips, ~900x500μm, coarsely pre-positioned (manually)  
 To final state in ~5 seconds

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## C2F CHIP2FOIL

- Chip2Foil main aim: *to develop a technology platform for high speed, low cost placement and interconnection of ultra thin chips on thin polymer foils*
- EU FP7 funded STREP
- Call ICT-2009.3.3 – Flexible, organic and large area electronics
- Started Jan 1, 2010; duration 3 years
- ~€4.7 project size, ~€2.9 EU contribution

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## Communicative foil-based packages

- Increased interaction packed product – package – environment
- Chip2Foil focused case: Smart Blister to ensure therapy compliance

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## Demands

**Flexible package**

- Foil-based thin package, 30-50µm
- Ultra thin chip (UTC), 15-20µm

**Advanced RFID chips**

- 20-40IO
- Clock function

**Low cost**

- Single foil
- PET
- Single chip, 1x1mm<sup>2</sup>

**High volume**

- Billions of packages/yr, 10-50 chips/s
- Reel-to-reel compatible

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## Functions communicative foils

- Focus of Chip2Foil: ultra thin chip integration

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## Process progress

- **Self-assembly:** high throughput and low cost, moderate precision
- **Adaptive circuitry:** flexible low-cost interconnection

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## Rationale behind the concept

Redistributing the precision budget

- Allowable initial misalignment 1mm**
  - Contactless chip presentation
  - Presentation to moving web
  - Presentation on "mobility enhancing" mechanism
- Self-assembly**
  - From very coarse (initial misalignment) to ~40-50µm
  - Speed and throughput is main issue
- Mechanical bonding**
  - Globtop
- Adaptive interconnection**
  - Measure chip position
  - "Write" IO specific interconnects
  - Compensate for alignment errors

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### Chip2Foil technical work

- UTC assembly:
  - Chip thinning – relationship chip thickness and functionality, chip thickness and process compliance
  - UTC release and presentation
  - Self-assembly
  - Mechanical bonding
- Adaptive interconnection
  - Chip position registration
  - Interconnect technology, use of laser machining

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### Self-assembly: use of magnetic forces

- Two principles:
  - $F_{\text{magnetic}}$  proportional to gradient of magnetic field (square)
  - Shape anisotropy: field lines like to follow path of least resistance

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### Design

- Magnetic field lines focused by flux guides on substrate
- Flux guides on chip to be aligned make chip susceptible to field

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### Design

- Magnetic field lines focused by flux guides on substrate
- Flux guides on chip to be aligned make chip susceptible to field
- Enhance chip mobility: air cushion
- Self-assembly on
  - Foil → perforations, sloppy foil
  - Tool → transfer step needed to foil

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### Initial result

- 3mm x 3mm parts
- Alignment accuracy 40 μm and 55 μm in x, y directions resp.
- Rotational alignment accuracy of 6°
- Fastest alignment is in 0.4 sec
- Allowable initial misalignment ~ 1 chip size (!)

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### Initial misalignment range

Max alignment distance (X and Y) [μm]	Alignment distance [μm]
0	~3500
500	~3500
1000	~3500
1500	~3500
2000	~1500
2500	~500
3000	~0

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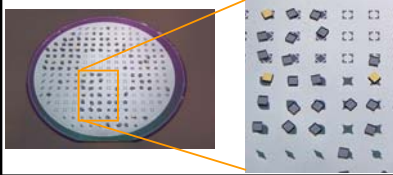
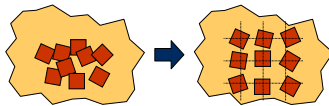
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- **Self-assembly towards industrialisation**

## Conclusions and suggestions

- Self-assembly can be promising approach to make breakthrough in assembly process performance
- The field needs industrialisation: demonstrate potential in real and relevant industrial case
- Possible approach:
  - Decompose assembly process in elementary operations
  - Develop single, linkable competences

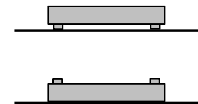
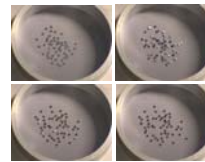
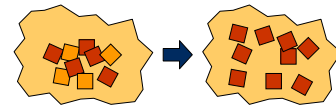
## Example “elementary operations”

- Spread parts



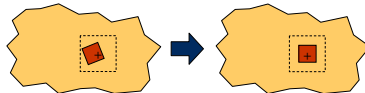
## Example “elementary operations”

- Flip parts



## Conclusions and suggestions

- Likely successful operation: self-alignment



- Requires high-throughput low cost presentation approaches
- Teaming up of engineering scientists with innovative industrialists